

XEI SCIENTIFIC, INC.

Evactron® RF Plasma Cleaning Systems for Electron Microscopes

CE Declaration of Conformity

Manufacturer: XEI Scientific, Inc.
1755 East Bayshore Rd. Ste. 17, Redwood City, CA 94063
(650) 369-0133, FAX (650) 363-1659
www.Evactron.com, Rvane@Evactron.com

Model: Evactron® Model E50 De-Contaminator

Type of Equipment: RF Plasma Cleaning System for vacuum systems

Application of Council Directives(s): EC Directive 2014/35/EU (Low Voltage Directive)
2011/65/EU (RoHS)
2014/30/EU EMC directive

Testing Provider Notified Body, and Certification body: TUV Rheinland of North America, San Francisco Office
1279 Quarry Lane
Pleasanton, CA 94586

Tests: Confirmation of conformity to the Low Voltage and Machinery Directive:
IEC 61010-1:2010 & Annex I of 2006/42/EC (Machinery Directive)
TUV: report number 31771961.001

Certificate of Conformity to Electromagnetic Compatibility
EC Directive 2014/35/EU
Tested acc. to: EN 61326-1:2013
EN 55011:2009+A1:2010, CISPR 11:2009+A1:2010,
FCC Part 18:2017, ICES-001:2006
TUV Report Nos. 31762450.001
Registration No. AE 72032483 0001

I, the Undersigned, hereby declare that the equipment above conforms to the above Directives and Standards, when installed in accordance with the manufacturer's specifications.

Place of Issue: Redwood City, CA

Date of Issue: Dec. 20, 2017

Ronald Vane

Ronald Vane - President